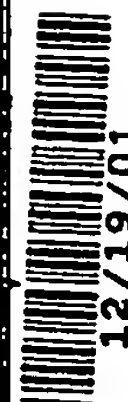


U.S. Department of Commerce, Patent and Trademark Office				Atty Docket No.		Serial No.	
				M-12332 US		Unknown	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Applicants			
(Use several sheets if necessary)				Pablo I. Rovira and Lars Markwort			
				Filing Date		Group	
				Herewith		Unknown	
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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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							Translation
		Document	Date	Country	Class	Subclass	Yes No
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	AJ						
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	AB							
	AC							
	AD							
	AE			<i>None</i>				
	AF							
	AG							
	AH							
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AI							
	AJ			<i>None</i>				
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<i>180</i>	AK	Kazama, A. et al., "Compact and high-speed ellipsometer" <i>SPIE</i> Vol. 1681 Pages (1992) 183-188.						
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<i>180</i>	AP	Chapter 3, Ellipsometer Systems, "Theory and Analysis of Measurements in Ellipsometer Systems" Pages 167-268.						
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